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Form PTO-149		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1299		SERIAL NO. 09/428,125	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Vishnu K. Agarwal et al.			
				FILING DATE October 26, 1999		GROUP 2822	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
KR	AA	3,886,415	05/27/75	Genthe			
	AB	5,438,012	08/01/95	Kamiyama			
	AC	5,665,210	09/09/97	Yamazaki			
	AD	5,675,028	10/07/97	Neumayer et al.			
	AE	5,723,382	03/03/98	Sandhu et al.			
	AF	5,858,873	01/12/99	Vitkavage et al.			
	AG	5,985,714	11/16/99	Sandhu et al.			
	AH	6,017,789	01/25/00	Sandhu et al.			
	AI	6,028,359	02/22/00	Merchant et al.			
	AJ	6,081,034	06/27/00	Sandhu et al.			
	AK	6,090,659	07/18/00	Laibowitz et al.			
	AL						
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		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
KR	AM	JP405211288A	08/20/93	Japan (Sakamoto)			
	AN	JP405243524A	09/21/93	Japan (Kamiyama)			
	AO	JP406061449A	0304/94	Japan (Kamiyama)			
	AP						
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
KR	AR		Chang et al.; "Structures of tantalum pentoxide thin films formed by reactive sputtering of Ta metal", Elsevier Science S.A. 1995, Thin Solid Films pps. 56-63				
	AS						
	AT						
EXAMINER				DATE CONSIDERED			
H. J. Rose				1/8/03			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							